



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: *Baer et al.*) Group No.: 1763
Serial No.: 10/675,697) Examiner: Arancibia
Filed: 09/30/2003) Docket No.: HSJ9-2003-0032US1

For: *"METHOD OF FORMING A READ SENSOR USING PHOTORESIST
STRUCTURES WITHOUT UNDERCUTS WHICH ARE REMOVED
USING CHEMICAL-MECHANICAL POLISHING (CMP) LIFT-OFF
PROCESSES"*

OK
to
enter
Maureen Gramaglia
9/11/2005

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REQUEST FOR RECONSIDERATION

The Applicant respectfully submits this Request for Reconsideration in response to the Office Action mailed on 23 May 2005 from Examiner Maureen Gramaglia Arancibia.